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DATE: Saturday, March 20, 2004

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<i>DB=USPT; PLUR=YES; OP=ADJ</i>			
<input type="checkbox"/>	L18	L16 and rpm	15
<input type="checkbox"/>	L17	L16 and ipa	3
<input type="checkbox"/>	L16	L15 and rotat\$	41
<input type="checkbox"/>	L15	((ultraso\$ or megaso\$) with nozzle) and 134/1.3 and wafer	50
<input type="checkbox"/>	L14	L11 and ((ultraso\$ or megaso\$) with nozzle)	6
<input type="checkbox"/>	L13	L10 and (ultraso\$ or megaso\$)	1
<input type="checkbox"/>	L12	L10 and ((ultraso\$ or megaso\$) with nozzle) (4401131 4985722 5061144 5081733 5092011 5144711 5213118 5226437 5236515 5261431 5278821 5282289 5297910 5327921 5345639 5370142 5375291 5498294 5503171 5509464 5520744 5626675 5651160 5730162 5927305 5975098 6021785)![pn]	27
<input type="checkbox"/>	L10	6431184.pn.	1
<input type="checkbox"/>	L9	(tokyo electron).as. and ipa and rpm and ((heated or heating or temperature) with water)	10
<input type="checkbox"/>	L8	l7 and ipa (4401131 4985722 5061144 5081733 5092011 5144711 5213118 5226437 5236515 5261431 5278821 5282289 5297910 5327921 5345639 5370142 5375291 5498294 5503171 5509464 5520744 5626675 5651160 5730162 5927305 5975098 6021785)![pn]	27
<input type="checkbox"/>	L6	L2 and heated	4
<input type="checkbox"/>	L5	L2 and heating	3
<input type="checkbox"/>	L4	L2 and heat\$	4
<input type="checkbox"/>	L3	L2 and temperature	4
<input type="checkbox"/>	L2	(tokyo electron).as. and ipa and rpm and (ultraso\$ or megaso\$)	5
<i>DB=USOC; PLUR=YES; OP=ADJ</i>			
<input type="checkbox"/>	L1	3062748.pn.	1

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<i>DB=USPT; PLUR=YES; OP=ADJ</i>				
<input type="checkbox"/>	L14	L11 and ((ultraso\$ or megaso\$) with nozzle)		6
<input type="checkbox"/>	L13	L10 and (ultraso\$ or megaso\$)		1
<input type="checkbox"/>	L12	L10 and ((ultraso\$ or megaso\$) with nozzle) (4401131 4985722 5061144 5081733 5092011 5144711 5213118		1
<input checked="" type="checkbox"/>	L11	5226437 5236515 5261431 5278821 5282289 5297910 5327921 5345639 5370142 5375291 5498294 5503171 5509464 5520744 5626675 5651160 5730162 5927305 5975098 6021785)![pn]		27
<input type="checkbox"/>	L10	6431184.pn.		1
<input type="checkbox"/>	L9	(tokyo electron).as. and ipa and rpm and ((heated or heating or temperature) with water)		10
<input type="checkbox"/>	L8	l7 and ipa (4401131 4985722 5061144 5081733 5092011 5144711 5213118		3
<input checked="" type="checkbox"/>	L7	5226437 5236515 5261431 5278821 5282289 5297910 5327921 5345639 5370142 5375291 5498294 5503171 5509464 5520744 5626675 5651160 5730162 5927305 5975098 6021785)![pn]		27
<input type="checkbox"/>	L6	L2 and heated		4
<input type="checkbox"/>	L5	L2 and heating		3
<input type="checkbox"/>	L4	L2 and heat\$		4
<input type="checkbox"/>	L3	L2 and temperature		4
<input type="checkbox"/>	L2	(tokyo electron).as. and ipa and rpm and (ultraso\$ or megaso\$)		5
<i>DB=USOC; PLUR=YES; OP=ADJ</i>				
<input type="checkbox"/>	L1	3062748.pn.		1

END OF SEARCH HISTORY

Day :
 Saturday
 Date:
 3/20/2004

Time:
 17:06:17

PALM INTRANET

Inventor Name Search Result

Your Search was:

Last Name = VERHAVERBEKE

First Name = STEVEN

Application#	Patent#	Status	Date Filed	Title	Inventor Name 51
60450117	Not Issued	020	02/25/2003	DILUTE SULFURIC PEROXIDE AT POINT-OF-USE	VERHAVERBEKE, STEVEN
60434188	Not Issued	020	12/16/2002	SINGLE WAFER CLEANING METHOD TO REDUCE PARTICLE DEFECTS ON A WAFER SURFACE	VERHAVERBEKE, STEVEN
60270815	Not Issued	159	02/23/2001	METHOD FOR ETCHING ELECTRONIC COMPONENTS CONTAINING TANTALUM	VERHAVERBEKE, STEVEN
60214116	Not Issued	159	06/26/2000	CLEANING METHOD AND SOLUTION FOR CLEANING A WAFER IN A SINGLE WAFER PROCESS	VERHAVERBEKE, STEVEN
60214115	Not Issued	159	06/26/2000	FULL WAFER MEGA SONICS COVERAGE	VERHAVERBEKE, STEVEN
60214073	Not Issued	159	06/26/2000	METHOD AND APPARATUS FOR REMOVING ADHERED MOISTURE FROM A WAFER	VERHAVERBEKE, STEVEN

<u>60214058</u>	Not Issued	159	06/26/2000	METHOD AND APPARATUS FOR DISSOLVING A GAS INTO A LIQUID FOR SINGLE WET WAFER PROCESSING	VERHAVERBEKE, STEVEN
<u>60214057</u>	Not Issued	159	06/26/2000	METHOD AND APPARATUS FOR FRONTSIDE AND BACKSIDE WET PROCESSING OF A WAFER	VERHAVERBEKE, STEVEN
<u>60214056</u>	Not Issued	159	06/26/2000	METHOD AND APPARATUS FOR CHEMICAL MIXING IN A SINGLE WAFER PROCESS	VERHAVERBEKE, STEVEN
<u>60214055</u>	Not Issued	159	06/26/2000	WAFER SPRAY CONFIGURATIONS FOR A SINGLE WAFER PROCESSING APPARATUS	VERHAVERBEKE, STEVEN
<u>60214054</u>	Not Issued	159	06/26/2000	ASSISTED RINNING IN A SINGLE WAFER CLEANING PROCESS	VERHAVERBEKE, STEVEN
<u>60188895</u>	Not Issued	159	03/13/2000	APPARATUS AND PROCESSES FOR REMOVING BULK PHOTORESIST	VERHAVERBEKE, STEVEN
<u>60168487</u>	Not Issued	159	12/02/1999	APPARATUS FOR PROVIDING OZONATED PROCESS FLUID AND METHODS FOR USING SAME	VERHAVERBEKE, STEVEN
<u>60020397</u>	Not Issued	159	06/25/1996	METHOD FOR SULFURIC ACID RESIST STRIPPING	VERHAVERBEKE, STEVEN
<u>10676182</u>	Not Issued	020	09/30/2003	DILUTE SULFURIC PEROXIDE AT POINT-OF-USE	VERHAVERBEKE, STEVEN
<u>10637725</u>	Not	020	08/07/2003	METHOD AND	VERHAVERBEKE,

	Issued			APPARATUS FOR DISSOLVING A GAS INTO A LIQUID FOR SINGLE WET WAFER PROCESSING	STEVEN
<u>10616093</u>	Not Issued	020	07/08/2003	ASSISTED RINSING IN A SINGLE WAFER CLEANING PROCESS	VERHAVERBEKE, STEVEN
<u>10407953</u>	Not Issued	030	04/04/2003	GUTTER AND SPLASH-GUARD FOR PROTECTING A WAFER DURING TRANSFER FROM A SINGLE WAFER CLEANING CHAMBER AND POSITIONING SUCH A WAFER IN THIS SINGLE WAFER CHAMBER	VERHAVERBEKE, STEVEN
<u>10407692</u>	Not Issued	030	04/03/2003	ROTATIONAL THERMOPHORETIC DRYING	VERHAVERBEKE, STEVEN
<u>10394465</u>	Not Issued	041	03/21/2003	USING SUPERCRITICAL FLUIDS AND/OR DENSE FLUIDS IN SEMICONDUCTOR APPLICATIONS	VERHAVERBEKE, STEVEN
<u>10366103</u>	Not Issued	030	02/12/2003	METHOD AND APPARATUS FOR WAFER CLEANING	VERHAVERBEKE, STEVEN
<u>10349591</u>	Not Issued	030	01/22/2003	RATE MONITOR FOR WET WAFER CLEANING	VERHAVERBEKE, STEVEN
<u>10229446</u>	Not Issued	030	08/27/2002	METHOD AND APPARATUS FOR PROCESSING A WAFER	VERHAVERBEKE, STEVEN
<u>10194605</u>	Not Issued	161	07/12/2002	METHOD AND COMPOSITION FOR CHEMICAL POLISHING	VERHAVERBEKE, STEVEN

<u>10188174</u>	Not Issued	061	07/01/2002	USING A TIME CRITICAL WAFER CLEANING SOLUTION BY COMBINING A CHELATING AGENT WITH AN OXIDIZER AT POINT-OF-USE	VERHAVERBEKE, STEVEN
<u>10187571</u>	Not Issued	030	07/01/2002	POINT-OF-USE MIXING WITH H2SO4 AND H2O2 ON TOP OF A HORIZONTALLY SPINNING WAFER	VERHAVERBEKE, STEVEN
<u>10121635</u>	Not Issued	030	04/11/2002	METHOD AND APPARATUS FOR WAFER CLEANING	VERHAVERBEKE, STEVEN
<u>10113495</u>	Not Issued	041	03/29/2002	GUTTER AND SPLASH-GUARD FOR PROTECTING A WAFER DURING TRANSFER FROM A SINGLE WAFER CLEANING CHAMBER	VERHAVERBEKE, STEVEN
<u>10097853</u>	Not Issued	041	03/12/2002	METHODS AND APPARATUSES FOR DRYING WAFER	VERHAVERBEKE, STEVEN
<u>10074516</u>	Not Issued	041	02/13/2002	METHOD FOR ETCHING ELECTRONIC COMPONENTS CONTAINING TANTALUM	VERHAVERBEKE, STEVEN
<u>09945454</u>	Not Issued	071	08/31/2001	METHOD AND APPARATUS FOR PROCESSING A WAFER	VERHAVERBEKE, STEVEN
<u>09892130</u>	Not Issued	071	06/25/2001	ASSISTED RINSING IN A SINGLE WAFER CLEANING PROCESS	VERHAVERBEKE, STEVEN
<u>09891989</u>	Not Issued	161	06/25/2001	CHUCK FOR HOLDING WAFER	VERHAVERBEKE, STEVEN

<u>09891890</u>	Not Issued	161	06/25/2001	METHOD AND APPARATUS FOR FRONTSIDE AND BACKSIDE WET PROCESSING OF A WAFER	VERHAVERBEKE, STEVEN
<u>09891849</u>	Not Issued	071	06/25/2001	METHOD AND APPARATUS FOR WAFER CLEANING	VERHAVERBEKE, STEVEN
<u>09891833</u>	Not Issued	071	06/25/2001	METHOD AND APPARATUS FOR CHEMICAL MIXING IN A SINGLE WAFER PROCESS	VERHAVERBEKE, STEVEN
<u>09891829</u>	Not Issued	041	06/25/2001	METHOD AND APPARATUS FOR DISSOLVING A GAS INTO A LIQUID FOR SINGLE WET WAFER PROCESSING	VERHAVERBEKE, STEVEN
<u>09891791</u>	Not Issued	161	06/25/2001	WAFER SPRAY CONFIGURATIONS FOR A SINGLE WAFER PROCESSING APPARATUS	VERHAVERBEKE, STEVEN
<u>09891730</u>	Not Issued	071	06/25/2001	CLEANING METHOD AND SOLUTION FOR CLEANING A WAFER IN A SINGLE WAFER PROCESS	VERHAVERBEKE, STEVEN
<u>09891259</u>	Not Issued	164	06/25/2001	METHOD AND APPARATUS FOR REMOVING ADHERED MOISTURE FORM A WAFER	VERHAVERBEKE, STEVEN VERHAVERBEKE
<u>09843229</u>	6524940	150	04/26/2001	METHODS AND DEVICES UTILIZING THE AMMONIUM TERMINATION OF SILICON DIOXIDE FILMS	VERHAVERBEKE, STEVEN
<u>09805348</u>	6491763	150	03/13/2001	PROCESSES FOR	VERHAVERBEKE,

				TREATING ELECTRONIC COMPONENTS	STEVEN
<u>09755720</u>	Not Issued	161	01/04/2001	RINSING SOLUTION AND RINSING AND DRYING METHODS FOR THE PREVENTION OF WATERMARK FORMATION ON A SURFACE	VERHAVERBEKE, STEVEN
<u>09727661</u>	Not Issued	161	12/01/2000	APPARATUS FOR PROVIDING OZONATED PROCESS FLUID AND METHODS FOR USING SAME	VERHAVERBEKE, STEVEN
<u>09603792</u>	Not Issued	161	06/26/2000	MEGASONICS APPLICATED ON THE BACKSIDE AND GOING THROUGH THE WAFER	VERHAVERBEKE, STEVEN
<u>09574790</u>	Not Issued	161	05/19/2000	METHODS FOR WET PROCESSING ELECTRONIC COMPONENTS HAVING COPPER CONTAINING SURFACES	VERHAVERBEKE, STEVEN
<u>09495399</u>	Not Issued	161	01/31/2000	WET PROCESSING METHODS FOR THE MANUFACTURE OF ELECTRONIC COMPONENTS USING LIQUIDS OF VARYING DENSITY	VERHAVERBEKE, STEVEN
<u>09478094</u>	6517636	150	01/05/2000	METHOD FOR REDUCING PARTICLE CONTAMINATION DURING THE WET PROCESSING OF SEMICONDUCTOR SUBSTRATES	VERHAVERBEKE, STEVEN

09456585	Not Issued	161	12/08/1999	METHOD FOR PREPARING SILICON SURFACES FOR HEMISPHERICAL GRAIN GROWTH	VERHAVERBEKE, STEVEN
09253157	Not Issued	161	02/19/1999	METHODS OF WET PROCESSING ELECTRONIC COMPONENTS USING PROCESS LIQUIDS WITH CONTROLLED LEVELS OF GASES	VERHAVERBEKE , STEVEN
08684543	6132522	150	07/19/1996	WET PROCESSING METHODS FOR THE MANUFACTURE OF ELECTRONIC COMPONENTS USING SEQUENTIAL CHEMICAL PROCESSING	VERHAVERBEKE , STEVEN

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Application Number Information

Application Number: **60/214054 Order This File Assignments**

Examiner Number: **00000 /**

Filing Date: **06/26/2000**

Group Art Unit: **0000**

Effective Date: **06/26/2000**

Class/Subclass: **/.**

Application Received: **06/28/2000**

Lost Case: **NO**

Patent Number:

Interference Number:

Issue Date: **00/00/0000**

Unmatched Petition: **NO**

Date of Abandonment: **00/00/0000**

L&R Code: Secrecy Code: **1**

Attorney Docket Number:
4733/TCG/OTHER/LE

Third Level Review: **NO** Secrecy Order: **NO**

Status: **159 /PROVISIONAL APPLICATION EXPIRED**

Status Date:
08/31/2003

Confirmation Number: **3634**

Oral Hearing: **NO**

Title of Invention: **ASSISTED RINSING IN A SINGLE WAFER CLEANING PROCESS**

Bar Code	PALM Location	Location Date	Charge to Loc	Charge to Name	Employee Name	Location
60214054	9200	06/04/2001	No Charge to Location	No Charge to Name	LOE CONV DR1995U	

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Application Number Information

Application Number: **10/616093**

Examiner Number: **00000 /**

Assignments

Filing Date: **07/08/2003**

Group Art Unit: **1746 IFW IMAGE**

Effective Date: **07/08/2003**

Class/Subclass:

134/033.000

Application Received: **07/10/2003**

Lost Case: **NO**

Patent Number:

Interference Number:

Issue Date: **00/00/0000**

Unmatched Petition: **NO**

Date of Abandonment: **00/00/0000**

L&R Code: Secrecy Code:**1**

Attorney Docket Number: **4733 USA
D01/TCG/TPG/OTHE**

Third Level Review: **NO** Secrecy Order: **NO**

Status: **20 /APPLICATION DISPATCHED FROM PREEXAM,
NOT YET DOCKETED**

Status Date:
10/06/2003

Confirmation Number: **9641**

Oral Hearing: **NO**

Title of Invention: **ASSISTED RINSING IN A SINGLE WAFER CLEANING PROCESS**

Bar Code	PALM Location	Location Date	Charge to Loc	Charge to Name	Employee Name	Location

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